

**PATENT APPLICATION**  
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q90414

Hiroyuki AKAGAWA

Appln. No.: 10/549,901

Group Art Unit: 1795

Confirmation No.: 7222

Examiner: Stewart A. Fraser

Filed: September 20, 2005

For: SUBSTRATE FOR RETICLE AND METHOD FOR MANUFACTURING SUBSTRATE,  
AND MASK BLANK AND METHOD FOR MANUFACTURING MASK BLANK

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated October 1, 2008, please amend the above-identified application as follows on the accompanying pages.

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